

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: S. KADLEC, et al.
Serial No: 10/798,331
Filed: March 12, 2004
Title: METHOD FOR MANUFACTURING SPUTTER-COATED
SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING
CHAMBER WITH SUCH SOURCE
Group: 1753
Examiner: Michael A. Band
Conf. No.: 6134

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

December 6, 2007

Sir:

In response to the Office Action dated August 6, 2007, please amend the above-identified application as listed below and as set forth on the following pages:

Amendments to the Claims

Remarks are included following the amendments